## Con. 5432-07.

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## (3 Hours)

LSI Derign

N. B.: (1) Q. No. 1 is compulsory.

M.E. SemIL (Etox)

- (2) Attempt any four out of remaining six questions.
- (3) Assume any suitable data wherever required but justify the same.
- a Define Inverter Ratio. and state its significance.
  - b What is burried contact? When we use this in MOS technology
  - c Compare between Silicon and Germanium Technology..
  - d Define Sheet Resistance, What is the significance of it?
  - e Draw the Exclusive OR using minimum devices in CMOS Technology?

2 a Implement following function also draw the stick diagram

F = X + (Y. Z)

Draw Layout for the same.

- b Using nMOS devices design 4:1 MUX also draw the stick diagram. 10
- a Explain the effect of scaling on interconnect with respect to power 10 dissipation and delay
  - b Describe with neat diagram various steps involved in fabrication and 10 sketch each mask steps in cross-sectional view of wafer for nMOS device.
- 4 a Derive expression for nMOS transistor current in both regions of 10 operations.
  - Find the expression for Threshold voltage of pMOS device also 10
    explain the effect of substrate potential( Body Effect)on Threshold & overall performance of the device
- 5 a Explain following short channel effects:
  - i) Threshold voltage roll off
  - ii) Drain Punch-through
  - iii) Velocity saturation
  - iv) Hot carrier effect.
  - b Prepare a chart of CMOS Inverter characteristics in five different
    10 regions. Specify for the devices the region of operation and justify.

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Total Marks : 100

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- 6 a Derive Noise margin for Resistive load type of an Inverter
  - b What is total power dissipation in case of CMOS Inverter? Discuss
    10 how to approximate the estimation of total power dissipation? What
    is power budget ? how to minimize the Power Dissipation?
  - Write short notes on: (any four):
    - a CMOS Domino Logic
    - b Explain MOS Capacitor and Band Bending in P-type of Semiconductor.
    - c Need & Effect of scaling.
  - d Latch-up problem in CMOS device
  - e Electron beam lithography
  - f Super buffer and its importance in IC design

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